

CLAIMS

1. A substrate processing module comprising:
a first tank and a second tank that are arranged
5 in a first direction and in which a substrate can be placed;
a first conveyor that moves the substrate
linearly in the first direction;
a second conveyor that moves the substrate
linearly in a second direction intersecting the first
10 direction; and
a vertical conveyor that vertically moves the
substrate,
wherein the vertical conveyor is connected to
the first conveyor, and the first conveyor moves the vertical
15 conveyor in the first direction,
and wherein an another module is allowed to be
connected in the second direction.
2. The substrate processing module according to
20 claim 1, wherein the second conveyor is configured as being
separate from the first conveyor and located above the first
conveyor, and the substrate is delivered between the first
conveyor and the second conveyor above the first conveyor.
- 25 3. The substrate processing module according to

claim 1 or 2, wherein an actuator of the second conveyor is used in common with the another module.

4. The substrate processing module according to
5 any one of claims 1 to 3, wherein

each module has a rail to support an actuator
main body portion of the second conveyor with being movable
in the second direction, and when the another module is
connected, a rail of the substrate processing module and a
10 rail of the another module are arranged in the second
direction to form a continuous track.

5. The substrate processing module according to
any one of claims 1 to 4, further comprising a pair of side
15 walls sandwiching the first tank and the second tank in the
second direction,

wherein the side walls have openings through
which the second conveyor passes.

20 6. The substrate processing module according to
any one of claims 1 to 5, wherein

the first tank is arranged on a front side in
the first direction,

the second tank is arranged on a rear side in
25 the first direction, and

the second conveyor moves the substrate above the first tank.

7. The substrate processing module according to
5 any one of claims 1 to 6, wherein each of the first tank and the second tank is any of a liquid chemical tank for processing the substrate with liquid chemical, a cleaning tank for cleaning the substrate, and a one-bath processing tank having a function of processing the substrate with
10 liquid chemical and a function of cleaning the substrate.

8. The substrate processing module according to claim 7, wherein

the first tank is a cleaning tank arranged on a
15 front side in the first direction, and

the second tank is a liquid chemical tank arranged on a rear side in the first direction.

9. The substrate processing module according to
20 any one of claims 1 to 8, wherein the another module connected to the substrate processing module in the second direction is any one of a loading module, an unloading module, a drying module, and a substrate processing module.

25 10. A substrate processing apparatus

comprising:

the substrate processing module according to any one of claims 1 to 9; and

the another module connected to the substrate processing module in the second direction.

11. A method of manufacturing a substrate, comprising:

a first conveyance step of conveying a substrate linearly in a first direction to move the substrate between a first tank and a second tank arranged in the first direction in a substrate processing module to which an another module is allowed to be connected in a second direction; and

a second conveyance step of conveying the substrate linearly in the second direction intersecting the first direction, wherein

the substrate is moved vertically in the first conveyance step.